Quantum Computing and Electron Beam Lithography

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How is a Quantum Computer Different?

	Classical Computer	Quantum Computer
Logic element	"Bit" : classical bit (transistor, spin in magnetic memory, …)	"Qubit" : quantum bit (any coherent two-level system)

Quantum computers may revolutionize high-performance computing.

Or they could be completely useless.

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Need: A quantum system with two energy levels

(0 and 1 states)

Choose: Superconducting LC Circuit

Macroscopic quantum system

Qubit Components

- Capacitors
- Inductors
- Signal Carrying Lines
- Non-linear Inductor (Josephson Junction)

Josephson Junction (JJ)

- Control: Send microwave pulses at qubit frequency to change qubit state
- Read out: Measure the resonator frequency which shifts depending on the qubit state

Superconducting Qubit Performance

Benefits of Superconducting Qubits

- Compatible with Si-based fabrication techniques
 - AI, Nb, Ta, TiN materials typically used
- Full control over device parameters
- Can manipulate and read out with off-the-shelf electronics

Want Longer Qubit Lifetime

Building a Superconducting Quantum Computer

Packaged Qubit Chip

Dilution Refrigerator and Control Electronics

- Packages shield qubits and provide access to control wiring
- Mount and measure qubits at mK temperatures
- Dilution refrigerators and control electronics can now be purchased commercially

Package Mounted in Dilution Refrigeration

Superconducting Qubit Community

Overall Goal: Fault-tolerant quantum processor for universal gate-based operation

Gold, et al., npj QI (2021)

Dickel *et al., PhysRev B* (2018) Foxen *et al.,* QS&T (2017) Grigoras *et al.*, arXiv:2201.10425 (2022) Yost*, Schwartz*, Mallek*, *et al.*, *npj QI* (2020) LINCOLN LABORATORY MASSACHUSETTS INSTITUTE OF TECHNOLOGY

Circuit elements fabricated using E-beam lithography

- Almost always: Josephson Junctions
- Group dependent: Everything else
 - Feedlines
 - Coplanar waveguide Resonators
 - Capacitors

Junction process flavors:

- Dolan bridge
- Manhattan
- Two-step Lithography

Dolan Process

Process Requirements

- Resist stack: e-beam bilayer (commonly MMA/PMMA, CSAR, ZEP)
- Moderate undercut needed
- Metal deposition needs tilt stage (+/- wafer tilt)

Pros/Cons

- Full JJ formed under vacuum
- Relatively compact design
- Suspended bridge limits design space
- Resist stack height dictates JJ overlap
 - But can be compensated by angle
- T-variant loses some tile-ability
 - But removes size dependence on resist height

Anastasiya A Pishchimova et al, Scientific Reports. 13. 10.1038/s41598-023-34051-9 2023

Manhattan Bridgeless Process

Process Requirements

- Resist stack: e-beam bilayer (commonly MMA/PMMA, CSAR, ZEP)
- Undercut for lift-off only
- Metal deposition needs tilt and rotation stage

Pros/Cons

- Full JJ formed under vacuum
- Easier fabrication process with no bridge
- JJ CDs are set by ebeam (resist height independent)
 - Until crossover from X to \Box layout
- Larger areas accessible with [] layout
- Some extra metal needed to connect to leads
- Not easily tiled in series

Zhang Ke et al, Chinese Physics B, 2017, 26(7): 078501 (2017)

Process Requirements

- Resist stack: PMMA for bottom electrode (BE), MAN for top electrode
- Subtractive etching landing on BE

Pros/Cons

- Manufacturable fabrication with no bridge or angled deposition
- JJ CDs are set by ebeam (resist height independent)
- Larger areas accessible
- Mill-in-the-middle required
- Extra processing steps
- Some extra metal needed to connect to leads

Jacques Van Damme et al, 0.48550/arXiv.2403.01312. (2024)

- Merged Element Transmon
 - Combination JJ and shunt-capacitor for smaller footprint device
 - Concentrates E+M energy inside the JJ, reducing relative participation at other interfaces

H.J. Mamin et al, Phys. Rev. Applied 16, 024023 (2021)

- Fluxonium
 - Qubit circuit that uses an inductor, typically made from a series chain of JJs

V. E. Manucharyan et al, Science 326, 113 (2009).

 Reduced sensitivity to dielectric loss and protection against quasiparticles at the small JJ lead to very high performance!

SEBL Parameters

- Beam current
- Spot size
- Beam step size
- Field sizes
- Dosing
- PEC

Device Parameters

- Feature size precision
- Feature size range
- Write speed
- Uniformity
- Line edge roughness
- Undercut requirements
- Ease of lift-off

Fundamental understanding and implementation of e-beam write parameters is critical to the fabrication of high quality superconducting qubit chips

Superconducting Qubit Development

- Quantum computers will do calculations in a new way to solve SOME kinds of hard problems
- We can make qubits from superconducting circuits
- E-beam lithography is highly used to pattern most sensitive circuit element, the Josephson junction
- Ongoing research to further improve device performance

EQuS I'lii

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